

サブテーマ名
小型高輝度X線発生装置を用いた
X線位相イメージング法の開発

東北大学 多元物質科学研究所
百生 敦

Margie P. Olbinado

Comparison of the X-ray Photon Count between 18.2 and 26.9 keV LCS X-ray mean energy Using the Rigaku HyPix3000 photon counting detector.

Figure 1. X-ray chart image using (a) 25 keV and (b) 17.5 keV LCS X-ray mean energy. Exposure time: 30 min

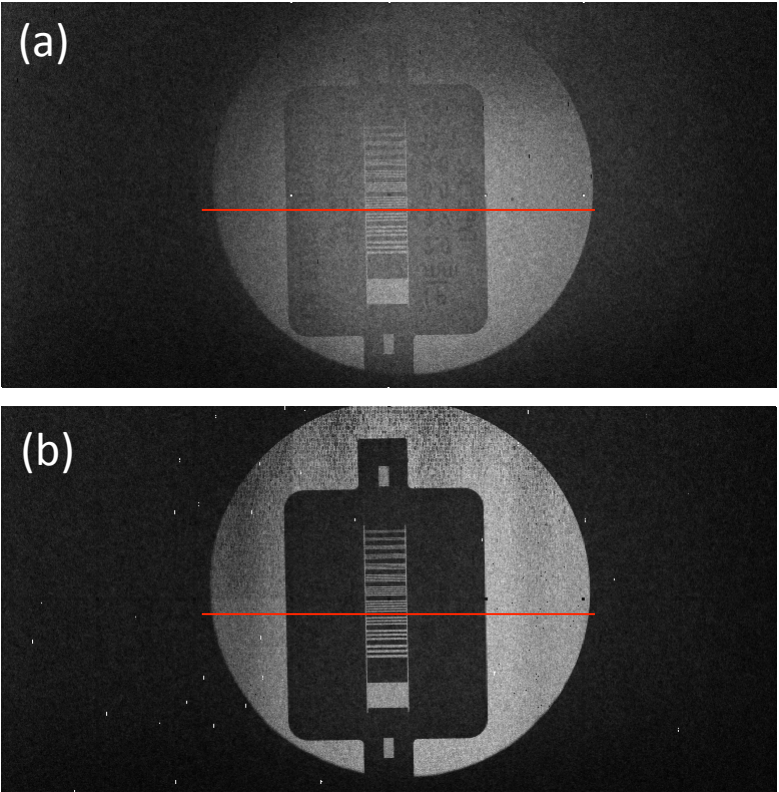
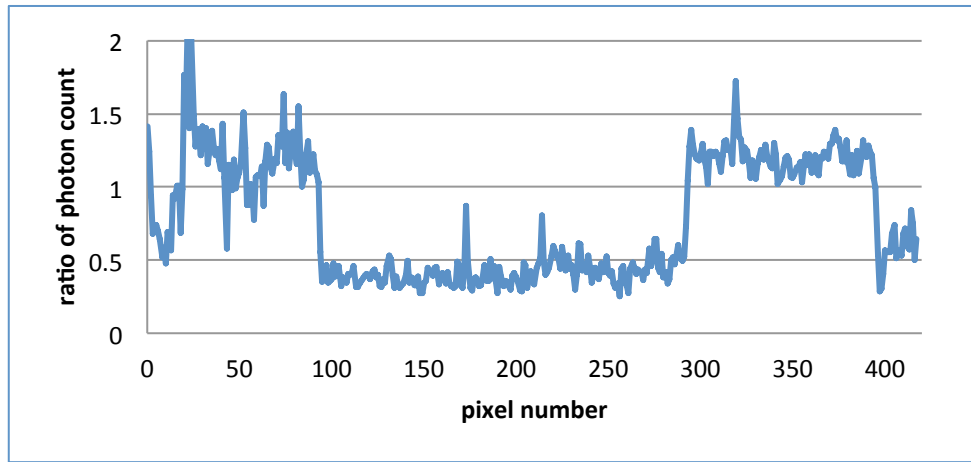


Figure 2. Plot of the Ratio of the photon counts across the line profiles in Figure 1.

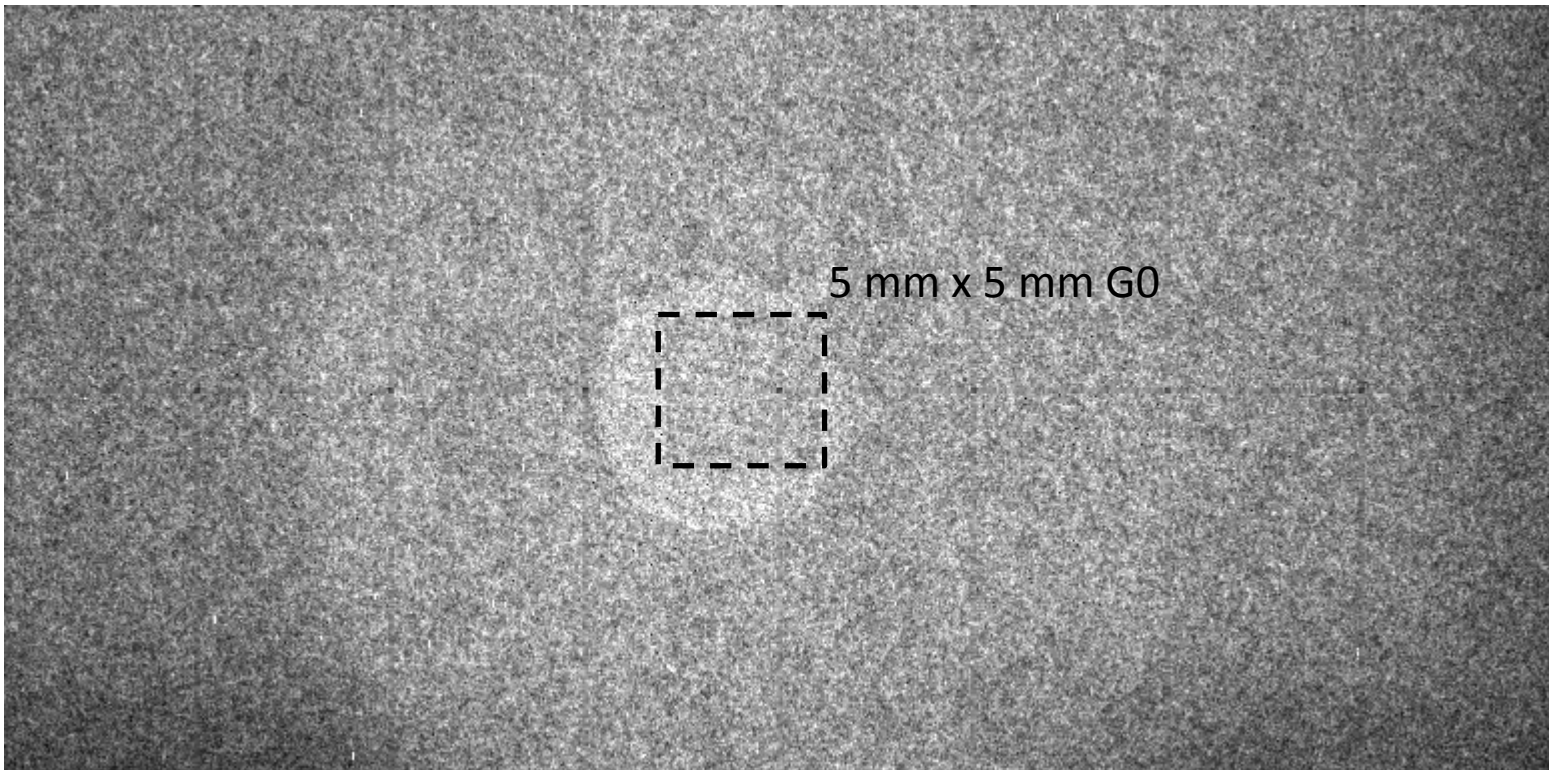
$$C_{\downarrow 18.2 \text{ keV}} / C_{\downarrow 26.9 \text{ keV}}$$



1. At regions outside the X-ray chart, the ratio of the X-ray photon count, $C_{\downarrow 18.2 \text{ keV}} / C_{\downarrow 26.9 \text{ keV}} \sim 1.2$ (ave).
2. At the region of the X-ray chart, the ratio of the X-ray photon count is ~ 0.4 (average) simply indicating that low energy X-rays are more absorbed by the Pb material of the X-ray chart.

Using LCS X-ray mean energy: 18.2 keV

- Gratings
 - G0: $d_0 = 30\text{um}$, $h_0 = 100\text{um}$, Area= **5mm x 5mm**
 - G1: $d_1 = 4.5\text{um}$, $h_1 = 1.8\text{um}$
 - G2: $d_2 = 5.3\text{um}$, $h_2 \sim 70\text{um}$
 - Si substrate thickness: 200 um (for each grating)
- R1= 963 mm
- z= 171 mm
- MOIRE WAS OBSERVED in one image before the Ti: Sapphire crystal of the laser was broken. Exposure time: 30 minutes obtained using HyPix-3000



Note on gratings' Si substrate thickness

Although the X-ray intensity was increased when the X-ray mean energy was lower (18.2 keV in comparison with 26.9 keV), there is less transmission of the lower energy X-rays through the Si substrates of the gratings.

Within 5mm x 5mm, the X-ray energy was 14 to 18 keV. The X-ray transmission through the Silicon substrates of the 3 gratings, which is 600 um (200um x 3 substrates), was :

50% for 18 keV X-rays

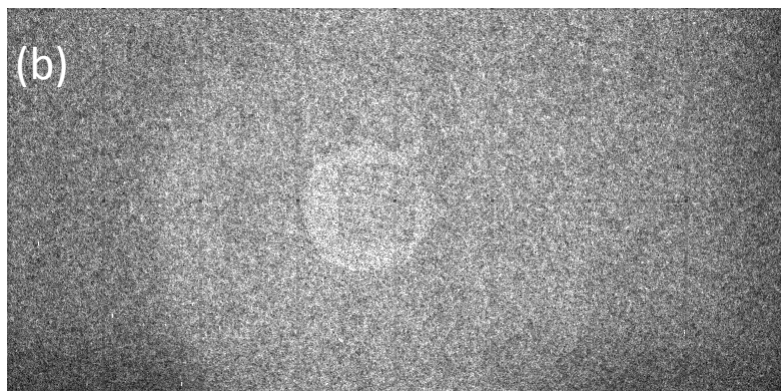
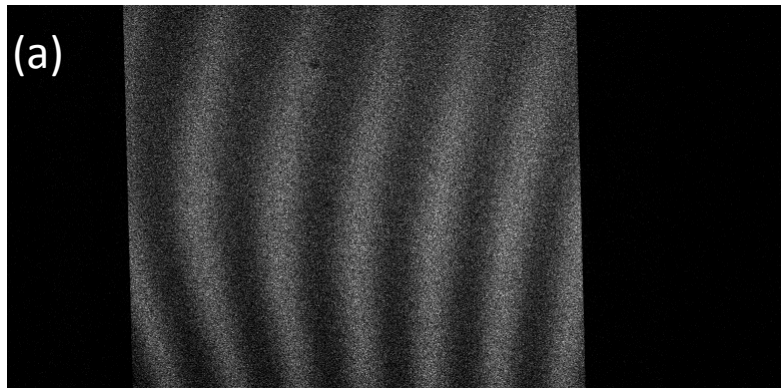
20% for 14 keV X-rays

Thinner Si substrate should be used when lower energy X-rays are to be utilized.

Comparison of the X-ray Photon Count between a rotating anode and an LCS X-ray source Using the Rigaku HyPix3000 photon counting detector.

Figure 3. Moiré images of a Talbot-Lau interferometer using:

(a) rotating anode X-ray source (40kV tube voltage and 45mA tube current), exposure time: 10 msec (b) LCS X-ray source with mean energy 18.2 keV, exposure time: 30 min



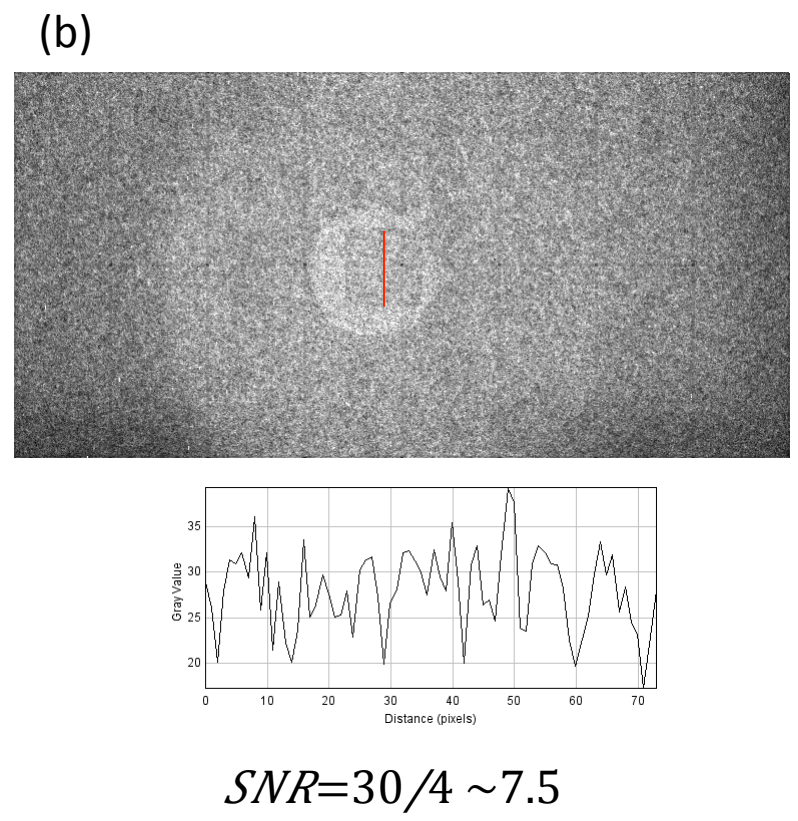
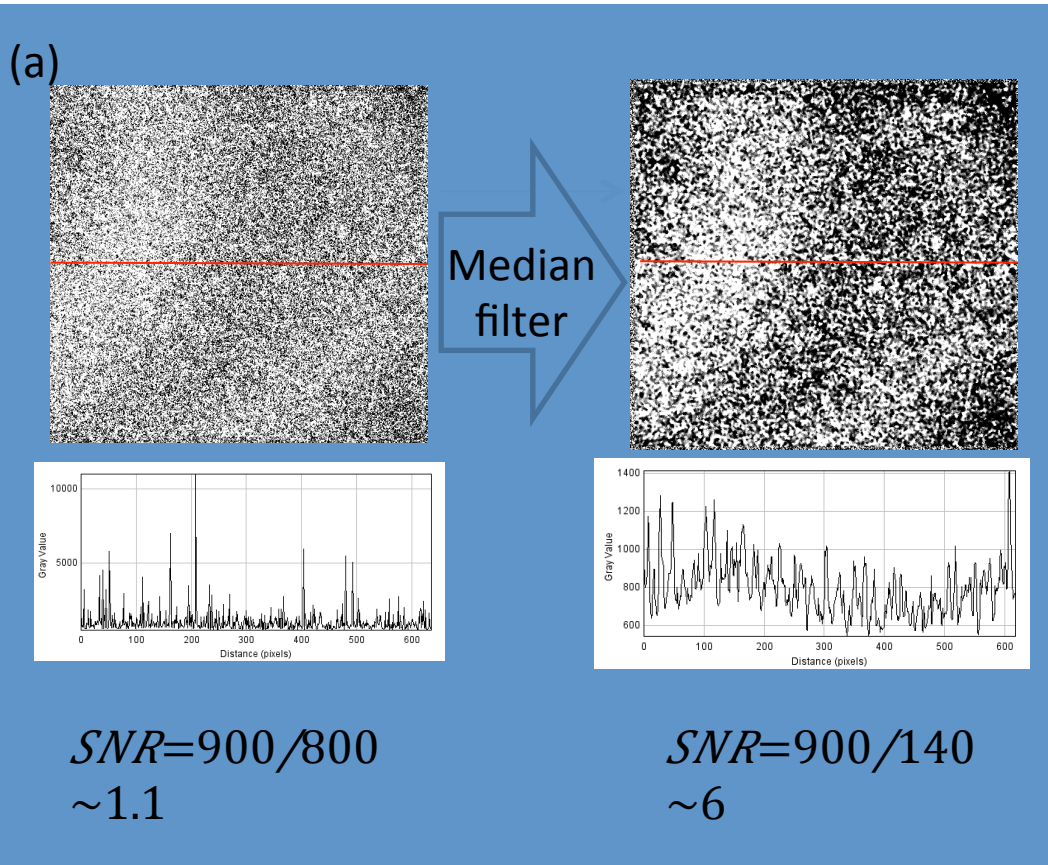
Ratio of the count rate:

$$\frac{R_{\text{rotating anode}}}{R_{\text{LCS X-ray source}}} = 750/\text{sec} / 0.015/\text{sec} = 50 \times 10^3$$

Comparison of the Signal to Noise Ratio between the AIST CCD-based X-ray detector and the Rigaku HyPix-3000 photon counting detector.

$$SNR = \frac{\text{bright fringe (average intensity)}}{\text{st.deviation}}$$

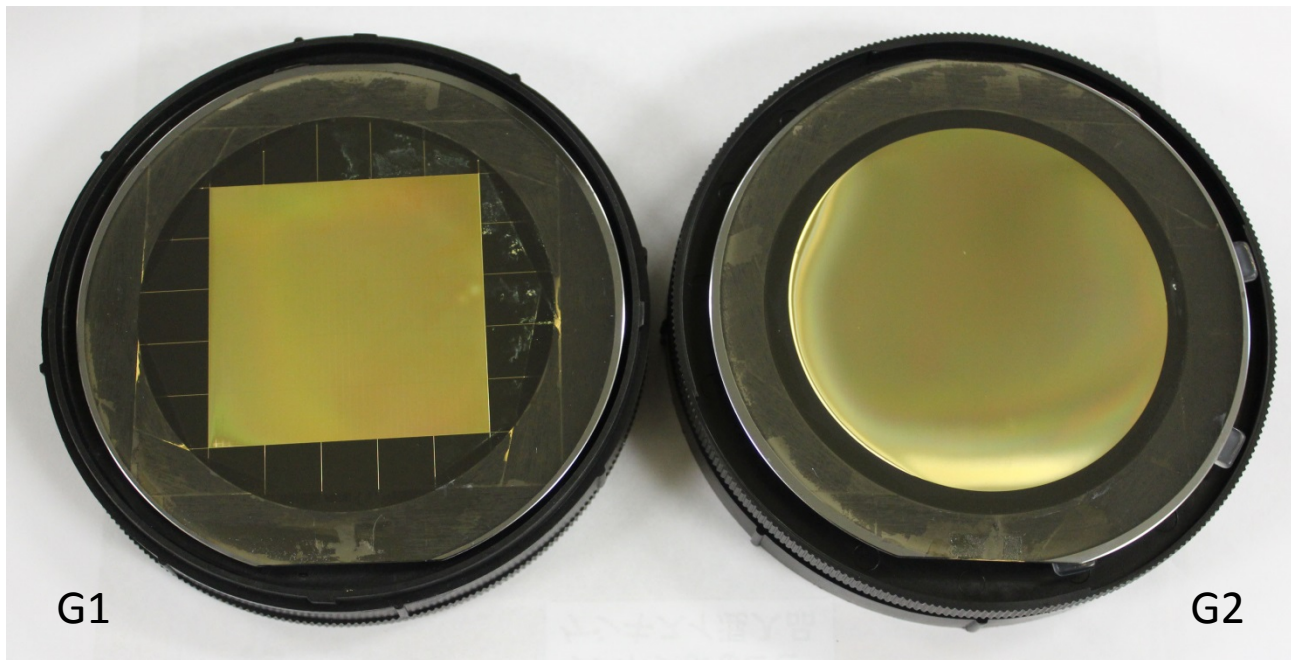
Figure 3. Moiré images of a Talbot-Lau interferometer using:
 (a) AIST CCD-based detector obtained in April 2014 (X-ray mean energy: 26.9 keV), exposure time: 30 min
 (b) Rigaku HyPix-3000 obtained in August 2014 (X-ray mean energy: 18.2 keV), exposure time: 30 min



X線格子

	Grating design	Grating period [μm] (Metal + Resist widths)	Grating area	Metal material	Metal thickness [μm] Absorption: -0%, +20% Phase: +/- 10%	Duty cycle = Metal/Period +/- 10%
G0 (Source)	bridges	6.82 (resist width 1.84)	50 mm x 50 mm	Au	> 70	0.73
G1 (Phase)	continuous	3.57	50 mm x 50 mm	Ni	5.23 ($\pi/2$ for 30 keV)	0.50
G2 (Absorption)	bridges	7.49	d = 70 mm	Au	100	0.50

← 発注



今後の予定

□AISTにおける位相イメージング実験再実験？

- G0納入(12月頃?)後に専用格子セットによる実験

□cERLでの実験準備

- AIST用格子セットの流用前提
30 keVでG0-G2間62cm。